# LVSD Subcommittee Meeting Minutes Kansas City, MO, USA October 17, 2018

## 1. Approval of meeting agenda

Motion to approve by Mike Lafond and second by Jeff Mizener with a unanimous approval.

## 2. Welcome and member attendance

The meeting was called to order by David Dunne at 3:45 PM. David welcomed the members and guests. 18 members and 7 guests were present. Membership total of 23, thus quorum threshold was met.

## 3. Introduction of members and guests

Introductions were made by each LVSD member and guest.

## 4. Approval of the minutes of the Spring 2018 LVSD meeting

The minutes of the April 25, 2018 meeting held in Orlando, FL were previously emailed to LVSD personnel. Motion to approve by Dean Sigmon and second by Tom Hawkins with a unanimous approval.

http://www.ewh.ieee.org/soc/pes/switchgear/minutes/2018-1/S18LVSDmiREV0.pdf

## 5. Update LVSD Roster and LVSD Document Status

An updated LVSD Roster was submitted for review and updating. The updated roster will be posted on the IEEE website.

http://www.ewh.ieee.org/soc/pes/switchgear/minutes/2018-1/F18LVSDa1REV0.pdf

An updated LVSD Document Status and Working Group/Task Force membership list was circulated to LVSD Working Group and Task Force members for updating. The updated document status will be posted on the IEEE website.

http://www.ewh.ieee.org/soc/pes/switchgear/minutes/2018-1/F18LVSDa2REV0.pdf

## 6. Working Group Status Reports

- a. C37.17: IEEE Standard for Trip Systems for Low-Voltage (1000 V and below) AC and General Purpose (1500 V and below) DC Power Circuit Breakers
  - i. 13 member 11 guests, Quorum met
  - ii. First Meeting
  - iii. 2 Sessions Spring 2019
- b. C37.13 : IEEE Standard for Low-Voltage AC Power Circuit Breakers Used in Enclosures
  - i. Keith Flowers Chair
  - ii. The decision was made to delay the first meeting until Spring 2019, due to personal reasons, so no working group minutes exist for Fall 2018.
  - iii. 2 Sessions Spring 2019

#### 7. Old Business

a. IEEE-SA Patent Policy

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The IEEE-SA patent policy is now reviewed and acknowledged during online meeting registration therefore slides are no longer required to be reviewed during every Working Group meeting. The patents materials are available at <a href="http://standards.ieee.org/board/pat/pat-slideset.pdf">http://standards.ieee.org/board/pat/pat-slideset.pdf</a>.

#### b. Visible Break Definition

A gap between conductors that can be visually verified, and meets the dielectric withstand requirements in relevant product standard

## 8. New Business

Dave shared a presentation from the Task Force on "IEEE 1547 influence on C37 standards" See attachment: F18LVSDa4REV0.pdf

## 9. Upcoming Meetings

Spring 2019	April 28 – May 1, 2019	Burlington Hilton, Burlington, VT
Fall 2019	October 6 – 10, 2019	Catamaran Resort, San Diego, CA
Spring 2020	May 4 - 8, 2020 Pepper	rmill Resort, Reno, NV
Fall 2020	October 4 - 8, 2020 She	eraton Sundance Square, Fort Worth, TX
Spring 2021	April 18-23, 2021 Hilton	Charlotte University Place, Charlotte, NC

#### 10. Adjourn

A motion to adjourn was made by Jeff Mizener and second by Clint Carnes. The meeting was adjourned at 4:07 PM.

Minutes submitted by:

Dan Hrncir, LVSD Secretary

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Attendance:	
Members:	Affiliation:
P. Barnhart	Underwriters Laboratories
T. Burse	Powell Industries
C. Carne	Schneider Electric
D. Delfino	General Electric
D. Dunne (Chair)	Schneider Electric
D. Edwards	Siemens Industry, Inc.
K. Flowers	Siemens Industry, Inc.
S. Gohil	AZZ / Central Electric Manufacturing Co.
L. Grahor	Eaton
T. Hawkins	Siemens Industry, Inc.
D. Hrncir (Secretary)	Eaton
M. LaFond	ABB
J. Mizener	Siemens Industry, Inc.
A. Morse	Siemens Industry, Inc.
D. Moser	ABB
T. Olsen	Siemens Industry, Inc.
R. Rohr	Powell Industries
D. Sigmon	Eaton
D. Signion	
Honorary Members:	Affiliation:
Guests:	Affiliation:
	Affiliation: Eaton (MR)
K. Sippel	
	Eaton (MR)
K. Sippel B. Armstrong	Eaton (MR) Meramec Instrument Transformers Co.
K. Sippel B. Armstrong M. Owens	Eaton (MR) Meramec Instrument Transformers Co. Eaton
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